

Few-Layer MoS₂ on AlN and AlTiO/p⁺-Si for Energy Device Applications

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Transition-metal dichalcogenides (TMDCs) van der Waals (VdW) layered materials and their alloys are significant potential in the area of transistors, light-emitting diodes, photodetectors, and energy devices. Especially, MoS₂ and WSe₂ are naturally *n*- and *p*-type TMDCs, respectively with bandgap E_g in the range of 2.1–1.2 eV and absorption coefficient α of $\sim 10^5$ cm⁻² exhibiting huge potential for advanced nanoscale optoelectronic and photovoltaic devices. However, the choice of the substrate plays a crucial role in the growth of uniform large-area film as well as scalable, defect-free, high-performance devices fabrication. Aluminum nitride (AlN) has a high E_g of approximately 6.24 eV, the thermal conductivity of 300 W/m-K, and a dielectric constant ϵ of 4.7 with the least lattice mismatch of $\sim 1.6\%$ (with MoS₂), whereas mist CVD AlTiO has high E_g of 5.12 eV and dielectric constant ϵ of 13.8 with the strong hydrophilic surface is found as promising substrates for the growth of large scale TMDCs [1,2]. Here, we report the growth of the few-layer large-scale MoS₂ and WS_{2-x}Se_x films on the AlN and AlTiO wafers by chemical vapor deposition (CVD) and mist-CVD. Further, we demonstrate the applications of MoS₂/AlN and WS_{2-x}Se_x/AlTiO/p⁺-Si structures as energy Devices. The photocurrent current of I_{ph} of 7×10^{-8} A with a responsivity of $\sim 1 \times 10^5$ AW⁻¹ was obtained in visible light at blue and red wavelengths in a WS_{0.3}Se_{1.7} photodetector (Figure 1). Further, the PCE of 3.1×10^{-3} with I_{ph} of 3×10^{-6} A/cm² with V_{oc} of 0.84 V and FF of 0.57 was achieved in WS_{0.3}Se_{1.7}-based in-plane *p*⁺-*n* solar cells fabricated on a high- κ mist CVD-AlTiO/p⁺-Si [4]. We will demonstrate the improved performance of few-layer mm-scale MoS₂/AlN, and WS_{2-x}Se_x/AlTiO/p⁺-Si structures photodetector and solar cell devices.

References

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Figures

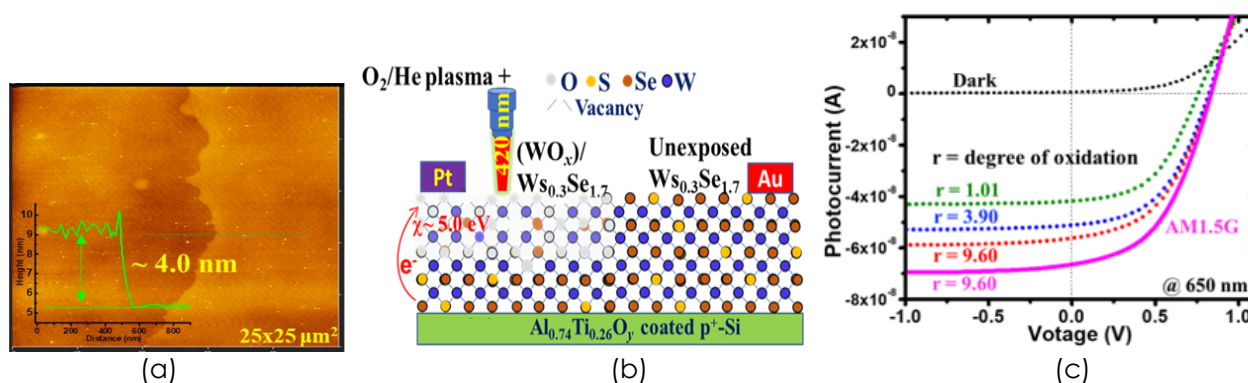


Figure 1: (a) AFM of few-layer WS_{2-x}Se_x film; (b) schematic of WS_{2-x}Se_x/AlTiO in-plane *p*⁺-*n* junction formed by plasma layer exposure; (c) *I*-*V* characteristics of devices at different degrees of oxidation.